

# 2, IDS  
Kuncan  
11-2-01

Customer No. 22,852  
Attorney Docket No. 04329.2620

jc872 U.S. PTO  
09/923443  
08/08/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Hiroshi NOMURA et al ) Group Art Unit:  
Serial No.: Not Yet Assigned ) Examiner:  
Filed: August 8, 2001 )  
For: EVALUATION MASK, FOCUS )  
MEASURING METHOD AND )  
ABERRATION MEASURING )  
METHOD )

Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicants bring to the Examiner's attention the documents listed on attached Form PTO-1449. Copies of the listed documents are attached. Applicants respectfully request that the Examiner consider the documents listed on attached Form PTO-1449 and indicate that they were considered by making an appropriate notation on this form.

This Information Disclosure Statement is being filed with the above-referenced application,

LAW OFFICES  
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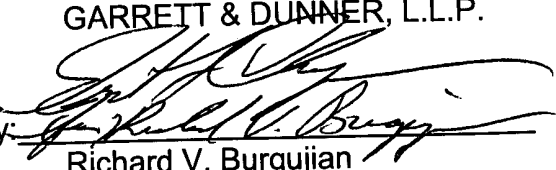
This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: August 8, 2001

By:   
Richard V. Burgujian  
Reg. No. 31,744

Enclosures  
EFC/FPD/bl

ERNEST F. CHAPMAN  
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## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	04329.26220	Serial No.	
Applicant	Hiroshi NOMURA and Kenji KONOMI		
Filing Date	August 8, 2001	Group:	

JCS72 U.S. PTO  
09/928448  
08/08/01

## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
	4,908,656	3/13/90	Suwa et al.			
	5,300,786	4/5/94	Brunner et al.			
	5,948,571	9/7/99	Mih et al.			
	6,011,611	1/4/00	Nomura et al.			
	6,114,096	9/5/00	Mih et al.			
	6,130,747	10/10/00	Nomura et al.			

## FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	T.A. Brunner et al., "QUANTITATIVE STEPPER METROLOGY USING THE FOCUS MONITOR TEST MASK", Optical/Laser Microlithography VII, Timothy A. Brunner ed., Proc. SPIE, Vol. 2197, pp 541-549 (1994).
	J.P. Kirk et al., "APPLICATION OF BLAZED GRATINGS FOR DETERMINATION OF EQUIVALENT PRIMARY AZIMUTHAL ABERRATIONS", Optical Microlithography XII, Luc Van den Hove ed., Proc. SPIE. Vol. 3679, 70-76 (1999)